



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Arkadiy Yampolskiy, et al. Art Unit : 3723
Serial No. : 09/903,052 Examiner : Lee D. Wilson
Filed : July 10, 2001
Title : CLOSED-LOOP CONTROL OF A CHEMICAL MECHANICAL POLISHER

MAIL STOP RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Applicants request consideration of the references listed on the attached PTO-1449 form. Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any listed U.S. patents or U.S. patent application publications can be provided upon request.

Further, in accordance with the provisions of 37 C.F.R. § 1.98(a)(3), Applicant submits that reference no. AL is not in the English language and directs the Examiner's attention to the English language abstract of same enclosed herewith for a concise statement as to its relevance.

This filing is being made with the filing of a Request for Continued Examination. No fee is required.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

December 5, 2005

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Applicant : Arkadiy Yampolskiy, et al.
Serial No. : 09/903,052
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Attorney's Docket No.: 05542-443001 /4738 USA02/CMP

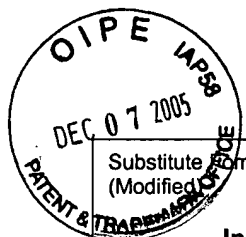
Respectfully submitted,

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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 05542-443001	Application No. 09/903,052
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Arkadiy Yampolskiy, et al.	
		Filing Date July 10, 2001	Group Art Unit 3723

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	2001/015811	08/23/2001	Ravid, et al.			
	AB	2001/026364	10/04/2001	Ravid, et al.			
	AC	2002/005957	01/17/2002	Moshe, et al.			
	AD	5,486,129	01/23/1996	Sandhu, et al.			
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	AG	6,159,073	12/12/2000	Wiswesser, et al.			
	AH	6,261,152 B1	07/17/2001	Aiyer			
	AI	6,829,054 B2	12/00/2004	Stanke, et al.			
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AL	JP 9148284	06/06/1997	JP				
	AM	WO 99/25520	05/27/1999	WIPO				
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AQ	Pan, J. Tony, et al., "Copper CMP and Process Control," Final Paper submitted to CMP-MIC Conference, February 11-12, 1999, Santa Clara, CA and Cambridge, MA, 7 pp.
	AR	Ravid, Avi, et al., "Copper CMP Planarity Control Using ITM," IEEE/SEMI Advanced Semiconductor Manufacturing Conference, 2000, pp. 437-443.
	AS	
	AT	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	